

**In the Claims:**

Please amend the claims as follows:

**CLAIMS**

1. (Currently Amended) A charged particle beam device (4) for inspecting or structuring a specimen (3) having comprising:
  - a charged particle beam source (5) to generate a charged particle beam (7);
  - a focussing lens (9) to focus the charged particle beam (7) onto the specimen (3); and
  - an aperture system (13) for defining an aperture (6) for the charged particle beam (7), the aperture system (13) comprising:
    - a first member (20) to block a first portion (7a) of the charged particle beam (7) between the charged particle beam source (5) and the focussing lens (9);
    - a second member (30) to block a second portion (7b) of the charged particle beam (7) between the charged particle beam source (5) and the focussing lens (9);
    - first means (24) for moving the first member (20) to adjust the a size of the a blocked first portion (7a) of the charged particle beam (7); and
    - second means (34) for moving the second member (30) independently of the first member (20).
2. (Currently Amended) The charged particle beam device according to claim 1, wherein ~~whereby~~ the first member (20) and the second member (30) have a respective first edge (22) and a second edge (32) capable of defining a respective first boundary (28) and a second boundary (38) of the aperture (6).
3. (Currently Amended) The charged particle beam device according to claim 2, wherein ~~whereby~~ the first edge (22) ~~and/or or~~ or the second edge (32) ~~are~~ is shaped to provide a first boundary (28) ~~and/or or~~ or a second boundary (38) which extend essentially linearly.

4. (Currently Amended) The charged particle beam device according to claim 2, wherein ~~whereby~~ the first edge (22) and the second edge (32) are shaped to provide a first boundary (28) and a second boundary (38) which extend essentially in parallel.
5. (Currently Amended) The charged particle beam device according to claim 2 ~~any one of the claims 2 to 4~~, wherein ~~whereby~~ the first edge (22) ~~and/or~~ or the second edge (32) ~~are~~ is shaped to provide an angled or rounded first ~~and/or~~ or second boundary (28; 38).
6. (Currently Amended) The charged particle beam device according to claim 2 ~~any one of the claims 2 to 5~~, wherein ~~whereby~~ the first means (24) ~~and/or~~ or the second means (34) for moving the respective first ~~and/or~~ or the second member (20; 30) ~~are~~ is capable of moving the respective first edge (22) ~~and/or~~ or second edge (32) without changing the shape of the aperture (6).
7. (Currently Amended) The charged particle beam device according to claim 1 ~~any one of the preceding claims~~, wherein ~~whereby~~ the first means (24) ~~and/or~~ or the second means (34) for moving the respective first ~~and/or~~ or second member (20; 30) each include a respective first motor ~~and/or~~ or a second motor ~~or, preferably, a respective first piezo drive and/or a second piezodrive~~.
8. (Currently Amended) The charged particle beam device according to claim 1 ~~any one of the preceding claims~~ further comprising a third, a fourth, a fifth, a sixth, a seventh ~~and/or~~ or an eighth members (40; 50; 60; 70; 80; 90) to selectively block respective third, fourth, fifth, sixth, seventh ~~and/or~~ or eighth portions (7d; 7e; 7f; 7g; 7h; 7i) of the charged particle beam (7) between the charged particle beam source (5) and the focussing lens (9).
9. (Currently Amended) The charged particle beam device according to claim 8 comprising a third, a fourth, a fifth, a sixth, a seventh ~~and/or~~ or an eighth means (44; 54;

~~64; 74; 84; 94~~) for moving the respective third, fourth, fifth, sixth, seventh ~~and/or~~ or eighth members (~~40; 50; 60; 70; 80; 90~~) to adjust the sizes of the blocked respective third, fourth, fifth, sixth, seventh ~~and/or~~ or eighth portions (~~7d; 7e; 7f; 7g; 7h; 7i~~) of the charged particle beam (7) independently of the respective other portions.

10. (Currently Amended) The charged particle beam device according to claim 8 ~~any one of the claims 8 or 9, wherein~~ whereby the third, fourth, fifth, sixth, seventh ~~and/or~~ or eighth member (~~40; 50; 60; 70; 80; 90~~) have respective third, fourth, fifth, sixth, seventh ~~and/or~~ or eighth edges (~~42; 52; 62; 72; 82; 92~~) capable of defining respective third, fourth, fifth, sixth, seventh ~~and/or~~ or eighth boundaries (~~48; 58; 68; 78; 88; 98~~) of the aperture (6).

11. (Currently Amended) The charged particle beam device according to claim 10, ~~wherein~~ whereby the third, fourth, fifth, sixth, seventh ~~and/or~~ or eighth edge (~~40; 50; 60; 70; 80; 90~~) is shaped to provide a respective third, fourth, fifth, sixth, seventh ~~and/or~~ or eighth boundary (~~48; 58; 68; 78; 88; 98~~) which extends essentially linearly.

12. (Currently Amended) The charged particle beam device according to any claim 10 ~~one of the claims 10 to 11, wherein~~ whereby the a third, a fourth, a fifth, a sixth, a seventh ~~and/or~~ or an eighth means (~~44; 54; 64; 74; 84; 94~~) for moving the respective third, fourth, fifth, sixth, seventh ~~and/or~~ or eighth member (~~40; 50; 60; 70; 80; 90~~) are each capable of moving the respective third, fourth, fifth, sixth, seventh ~~and/or~~ or eighth edges (~~42; 52; 62; 72; 82; 92~~) without changing the shape of the aperture (6).

13. (Currently Amended) The charged particle beam device according to claim 10 ~~any one of the claims 10 to 12, wherein~~ whereby the third edge (42) and the fourth edge (52), the fifth edge (62) and the sixth edge (72), ~~and/or~~ or the seventh edge (82) and the eighth edge (92) pair-wise extend essentially in parallel with a tolerance of less than 10 degrees ~~and, preferably, less than 5 degrees.~~

14. (Currently Amended) The charged particle beam device according to claim 9 ~~any one of the preceding claims, wherein whereby~~ the first, second, fourth, fifth, sixth, seventh and/or or eighth means ~~(24, 34, 44, 54, 64, 74, 84, 94)~~ for moving the respective first, second, fourth, fifth, sixth, seventh and/or or eighth members are capable of moving the respective member with steps having a step size smaller than 10  $\mu\text{m}$ , ~~preferably smaller than 1  $\mu\text{m}$  and even more preferred smaller than 0,1  $\mu\text{m}$ .~~

15. (Currently Amended) The charged particle beam device according to claim 9 ~~any one of the preceding claims, wherein whereby~~ the first, second, third, fourth, fifth, sixth, seventh and/or or eighth means ~~(24, 34, 44; 54; 64; 74; 84; 94)~~ for moving the respective first, second, third, fourth, fifth, sixth, seventh and/or or eighth member ~~(20, 30, 40; 50; 60; 70; 80; 90)~~ include a respective first, second, third, fourth, fifth, sixth, seventh and/or or eighth motor ~~or, preferably, a respective first, second third, fourth, fifth, sixth, seventh and/or or eighth piezo drive to move the respective first, second, third, fourth, fifth, sixth, seventh and/or or eighth edge (22, 32, 42; 52; 62; 72; 82; 92).~~

16. (Currently Amended) The charged particle beam device according to claim 1 ~~any one of the preceding claims, wherein whereby~~ the charged particle beam device ~~(1)~~ includes a scanning unit (17) to scan the charged particle beam ~~(7)~~ across the specimen ~~(3)~~.

17. (Currently Amended) The charged particle beam device according to claim 1 ~~any one of the preceding claims, wherein whereby~~ the charged particle beam device ~~(1)~~ is an electron beam device, ~~preferably a scanning electron microscope,~~ or a focussing ion beam device.

18. (Currently Amended) The charged particle beam device according ~~any one of the preceding claims~~ claim 1, wherein the charged particle beam device further comprising including a magnetic octupole component ~~(101) and/or or~~ an electrostatic octupole component ~~(101)~~.

19. (Currently Amended) The charged particle beam device according claim 1, wherein the charged particle beam device further comprising any one of the preceding claims including a magnetic hexapole component (404) and/or or an electrostatic hexapole component (404) to shape the charged particle beam (7).

20. (Currently Amended) The charged particle beam device according claim 8 ~~any one of the preceding claims~~ further having the first, second and third members (20; 30; 40) oriented to define a triangular aperture (6) for the charged particle beam (7).

21. (Currently Amended) Method for focussing a charged particle beam (7) onto a specimen (3), comprising with the steps:

providing a charged particle beam device (1) ~~according to any one of the preceding claims~~, wherein the charged particle beam comprises:

a charged particle beam source to generate a charged particle beam;

a focussing lens to focus the charged particle beam (7) onto a specimen; and

an aperture system (13) for defining an aperture (6) for the charged particle beam;

the aperture system comprising:

a first member to block a first portion of the charged particle beam between the charged particle beam source and the focussing lens;

a second member to block a second portion of the charged particle beam between the charged particle beam source and the focussing lens;

first means for moving the first member to adjust a size of the blocked first portion of the charged particle beam; and

second means for moving the second member independently of the first member;

generating the charged particle beam (7);

passing the charged particle beam (7) through a rectangular shaped aperture (6);

passing the charged particle beam (7) through a magnetic ~~and/or~~ or electric octupole field; and

directing the charged particle beam (7) onto the specimen (3).

22. (Currently Amended) Method for focussing a charged particle beam (7) onto a specimen (3) comprising with the steps:

providing a charged particle beam device (1) ~~according to any one of the preceding claims;~~ wherein the charged particle beam comprises;

a charged particle beam source to generate a charged particle beam;

a focussing lens to focus the charged particle beam (7) onto a specimen; and

an aperture system (13) for defining an aperture (6) for the charged particle beam;

the aperture system comprising:

a first member to block a first portion of the charged particle beam between the charged particle beam source and the focussing lens;

a second member to block a second portion of the charged particle beam between the charged particle beam source and the focussing lens;

first means for moving the first member to adjust a size of the blocked first portion of the charged particle beam; and

second means for moving the second member independently of the first member;

generating the charged particle beam (7);

passing the charged particle beam (7) through a triangular shaped aperture (6);

passing the charged particle beam (7) through a magnetic or electric hexapole field; and

directing the charged particle beam (7) onto the specimen (3).